

Inventors: Philip D. Floyd, et al.

Application No.: Not yet assigned

Filed: Concurrently herewith Examiner:

Title: METHOD AND APPARATUS FOR AN INTEGRATED LASER BEAM SCANNER

Group:

Commissioner for Patents Washington, D.C. 20231

Sir:

## PRELIMINARY AMENDMENT UNDER 37 C.F.R. § 1.173(b) ACCOMPANYING REQUEST FOR REISSUE OF U.S. PATENT NO. 6,002,507

Please enter this Preliminary Amendment into the file of the accompanying U.S. Patent Reissue Application.

## **IN THE CLAIMS:**

Please add new claims 21-36 as follows:

21. (NEW) A MEMS formation method including:

providing a SOI wafer including a single crystal silicon layer attached to an insulator layer;

forming at least one first MEMS component by patterning the single crystal silicon layer;

and

depositing at least one layer of polysilicon on the patterned single crystal silicon.

' 22. (NEW) The method of claim 21 further comprising forming at least one second MEMS component by patterning the polysilicon.